

## INFORMATION DISCLOSURE STATEMENT

Applicant : Hirayama et al.  
 App. No : 10/590,046  
 Filed : June 15, 2007  
 For : BASE MATERIAL FOR PATTERN-FORMING MATERIAL, POSITIVE RESIST COMPOSITION AND METHOD OF RESIST PATTERN FORMATION  
 Examiner : Johnson, Connie P.  
 Art Unit : 1795

### CERTIFICATE OF EFS WEB TRANSMISSION

I hereby certify that this correspondence, and any other attachment noted on the automated Acknowledgement Receipt, is being transmitted from within the Pacific Time zone to the Commissioner for Patents via the EFS Web server on:

March 15, 2011  
(Date)

/Neil S. Bartfeld/  
Neil S. Bartfeld, Ph.D., Reg. No. 39,901

Mail Stop Amendment  
 Commissioner for Patents  
 P.O. Box 1450  
 Alexandria, VA 22313-1450

Dear Sir:

Enclosed for filing in the above-identified application is a PTO/SB/08 Equivalent listing 1 (one) reference to be considered by the Examiner. Please place this document in the application file.

No fees are believed to be due. However, the Commissioner is hereby authorized to charge any additional fees which may be required to Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: March 15, 2011

By:

/Neil S. Bartfeld/

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